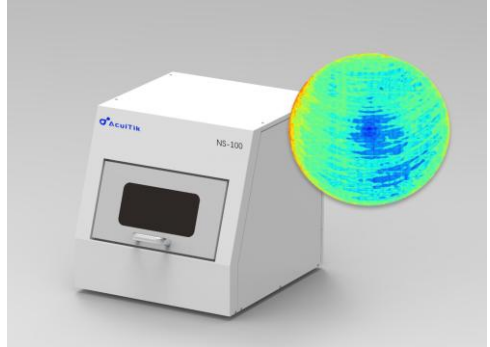




Film Thickness Measurement System **NanoSense**

NS-100 series (High Throughput)

- Scan the entire sample's film thickness, which is > 100 times faster than single-point measurement methods.
- Customizable integration into automated production lines.
- Measurement wavelength range covers 380 to 1700 nm.

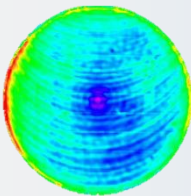


NS-30 mapping:
Single spot data
collection

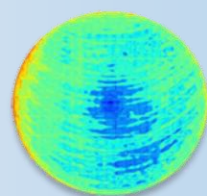


NS-100 mapping:
Line data
collection

12-inch wafer full mapping tests



70,000 measurement points cost
>48 hours



3 scans stitching cost less than 10
minute!